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Atty. Docket No. AMAT/4375/DD/BCVD/

A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
 Assistant Commissioner of Patents and Trademarks
 Washington, D.C. 20231

Re: Inventor(s): IAN LATCHFORD; CHRISTOPHER DENNIS BENCHER; YUXIANG WANG
 and MARIO DAVE SILVETTI
 Title: PHOTOLITHOGRAPHY SCHEME USING A SILICON CONTAINING
 RESIST

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 32 pages.
☒ Drawings totaling 12 pages, ☒ Formal Informal.
☒ Executed Declaration and Power of Attorney.
☒ Information Disclosure Statement w/ Form 1449 and References.
☒ Assignment of the invention to **Applied Materials, Inc.**
☒ Assignment Recordation Cover Sheet

jc971 U.S. PTO
 09/21/98
 08/02/01

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	44	-20=	24	x \$18.00	\$432.00
Independent Claims	3	-3=	0	x \$80.00	0
Basic Filing Fee				\$710.00	\$710.00
TOTAL FEES					\$1142.00

- ☒ The Commissioner is hereby authorized to charge \$1142.00 to Deposit Account No. 50-1074/4375/DD/BCVD/.
☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074/4375/DD/BCVD/. A duplicate copy of this transmittal is enclosed.
☒ Please address all future correspondence to:

**PATENT COUNSEL
 APPLIED MATERIALS, INC.
 Legal Affairs Department
 P.O. BOX 450A
 Santa Clara, CA. 95052**

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner of Patents and Trademarks, Washington, D.C. 20231

Express Mail Receipt No. EL849164081US

Date of Deposit 8-2-01

Signature Robert W. Mulcahy

Respectfully submitted,

Robert W. Mulcahy
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0921938.080201

jc928 U.S. PTO
 08/02/01